

Amendments to the Specification:

Please amend the specification by inserting the paragraph below, after the title on page 1.

Cross-Reference to Related Application

This application claims priority based on International Patent Application No. PCT/FR2003/050179, entitled "Method for Forming Patterns Aligned on Either Side of a Thin Film" by Maud Vinet, Simon Deleonibus, Bernard Previtali and Gilles Fanget, which claims priority of French Application No. 02/15980 filed on December 17, 2002, and which was not published in English.